

In Application of: Wolfgang M.J. Hofmann and Noel C. MacDonald	) ) )
Application No. Division of 10/021,311	) Group: )
Filed: Even date herewith	) Examiner: )
For: MULTIPLE-LEVEL ACTUATORS AND CLAMPING DEVICES	) )

JONES, TULLAR & COOPER, P.C.  
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October 7, 2003

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U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code <sup>2</sup> (if known)			
		5,198,390		MacDonald	03/03/1993	
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Substitute for form 1449A/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(use as many sheets as necessary)</i>			<b>Complete if Known</b>	
			Application Number	T, B, A.
			Filing Date	Even Date Herewith
			First Named Inventor	Wolfgang M.J. Hofmann
			Group Art Unit	1772
			Examiner Name	
Sheet 1	of 1	Attorney Docket Number	Hofmann	

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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
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		CHANG, T.H.P.k Kern, D.P., Muray, L.P.; Microminiaturization of electron optical systems; J. Vacuum Science & Technology B, vol. 8, pp. 1698-1705, 1990	
		CHANG, T.H.P., Kern, D.P., McCord, M.A., Muray, L.P.; A Scanning Tunneling Microscope Controlled Field Emission Microprobe System; J. Vacuum Science & Technology, vol. 9, pp. 438-443, 1991	
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		XU, Y., MacDonald, N.C., Miller, S.A.; Integrated Micro-scanning tunneling microscope; Applied Physics Letters, vol. 67, pp. 2305-7, 16 Oct. 1995.	
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		MACDONALD, N.C.; SCREAM Microelectromechanical systems; Microelectronic Engineering, vol. 32, pp. 49-73, Sept. 1996	
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